NE202 Jan and Aug 0:1

Micro and Nano Fabricaiton Lab

Instructor

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Email:

Department: Center for nano Science and Engineering

Course Time:

Lecture venue:

Detailed Course Page:

Announcements

Brief description of the course

The course is offered to students who are interested in micro and nano device fabrication. The focus of the course is to introduce unit fabrication process such as lithography, dry etch and deposition (dielectric, metal, semiconductor). The course is hand-on experience for the students.

The course is for postgrad and doctoral students.

Prerequisites

NE203-Advanced Micro and Nano Fabrication Process and technology is mandatory.

Syllabus

photolithography, ebeam lithography, LPCVD, PECVD, PVD, ebeam deposition, sputter deposition, wet etch, reactive ion-etching

Course outcomes

At the end of the course, the student should have hands-on experience and familiarity in using micro and nano fabrication process tools. The student should be able to independently develop process flow to fabricate a device and identify suitable unit process.

Grading policy

Quiz, interaction and runsheet - 50%

project - 50%

Assignments

Resources